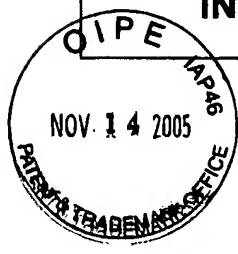


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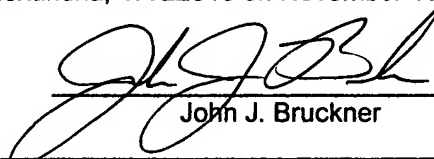
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE	
<b>INFORMATION DISCLOSURE STATEMENT</b>	Atty. Docket No. <b>UBAT1530</b>
Applicant(s) <b>Michael A. Guillorn</b>	
Application Number <b>10/716,770</b>	Date Filed <b>November 19, 2003</b>
For <b>VERTICALLY ALIGNED NANOSTRUCTURE SCANNING PROBE MICROSCOPE TIPS</b>	
Group Art Unit <b>2881</b>	Examiner <b>Fernandez, Kalimah</b>
Confirmation Number: <b>6209</b>	

Mail Stop Amendment  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**Certificate of Mailing Under 37 C.F.R. 1.8**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313 on November 10, 2005.

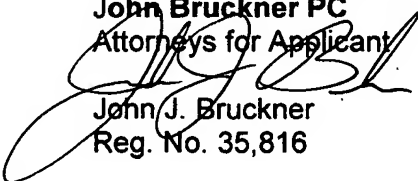
  
John J. Bruckner

Applicant respectfully requests, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the reference(s) listed on the attached PTO/SB/08A and/or PTO/SB/08B forms be considered and cited in the examination of the above-identified application. Pursuant to 37 C.F.R. §§ 1.97(g) and (h), no representation is made that a search has been made or that this art is material to the patentability of the present application.

Copies of the [non-US patent] reference(s) is(are) enclosed for the convenience of the Examiner. This Information Disclosure Statement is being filed after mailing of a First Office Action. Applicant hereby requests consideration of this Information Disclosure Statement pursuant to 37 C.F.R. § 1.97(c)(2).

A check in the amount of \$180 representing the fee set forth in 37 CFR § 1.17(p) is enclosed. While Applicants believe no (further) fees are due, if any (further) fees are due, the Commissioner is hereby authorized to charge any fees or credit any overpayments to Deposit Account No. 50-3204 of John Bruckner PC.

Dated: November 10, 2005  
5708 Back Bay Lane  
Austin, TX 78739  
Tel. (512) 394-0118  
Fax. (512) 394-0119

Respectfully submitted,  
**John Bruckner PC**  
Attorneys for Applicant  
  
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Reg. No. 35,816

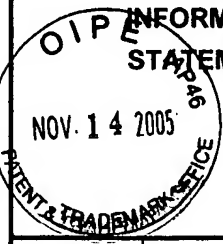
Application Number	10/716,770
Filing Date	November 19, 2003
First Named Inventor	Guillorn
Group Art Unit	2881
Examiner Name	Fernandez, Kalimah
Attorney Docket	UBAT1530

Sheet	1	of	1
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Examiner Initials	Cite No.	FOREIGN PATENT DOCUMENTS			Publication Date MM-DD-YYYY (Number 43)	Name of Patentee or Applicant of Cited Document
		Country Code	Number	Kind Code (if known)		

Date  
Considered

		<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>		Application Number	10/716,770
		Filing Date	November 19, 2003		
		First Named Inventor	Guillorn		
		Group Art Unit	2881		
		Examiner Name	Fernandez, Kalimah		
Sheet	1	of	2	Attorney Docket Number	UBAT1530

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		"Growth and fabrication with single-walled carbon nanotube probe microscopy tips" C.L. Cheung, J.H. Hafner, T.W. Odom, K. Kim and C.M. Lieber, Appl. Phys. Lett, <b>76</b> , 3136 (2000)
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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>				<b>Application Number</b>	<b>10/716,770</b>
				<b>Filing Date</b>	<b>November 19, 2003</b>
				<b>First Named Inventor</b>	<b>Guillorn</b>
				<b>Group Art Unit</b>	<b>2881</b>
				<b>Examiner Name</b>	<b>Fernandez, Kalimah</b>
<b>Sheet</b>	<b>2</b>	<b>of</b>	<b>2</b>	<b>Attorney Docket Number</b>	<b>UBAT1530</b>

### NON-PATENT LITERATURE DOCUMENTS

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Examiner Signature		Date Considered